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## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: Hung Nguyen
Kiyoshi ARAKAWA	)	
	:	Group Art Unit: 2851
Application No.: 10/622,143	)	
	:	Confirmation No.: 1879
Filed: July 18, 2003	)	
	:	Allowed: November 23, 2004
For: EXPOSURE APPARATUS, MAINTENANCE	)	
METHOD THEREFOR, SEMICONDUCTOR	:	
DEVICE MANUFACTURING METHOD	)	
USING THE APPARATUS, AND	:	
SEMICONDUCTOR MANUFACTURING	)	March 14, 2005
FACTORY	:	

## **Mail Stop ISSUE FEE**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## LETTER TRANSMITTING DOCUMENTS FOR PLACEMENT INTO OFFICIAL FILE

Sir:

For the convenience of the public, Applicant requests that the following documents be placed in the Official File: (1) February 14, 2005 European Search Report of a foreign counterpart application corresponding to the above-referenced application; (2) U.S. Patent No. 4,766,309 (Kudo); and (3) JP-A 6-275489 with English-language Abstract from Patent Abstracts of Japan, Vol. 18, No. 684 (E-1650).

The Search Report cites items (2) and (3), as well as EP 1 030 351, which is of record.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our below-listed address.

Respectfully submitted,

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